

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L6	825370	substrate wafer	US-PGPUB; USPAT; USOCR	OR	OFF	2005/09/28 15:39
L7	16510	L6 near manufactur\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:39
L8	4874	atom\$4 near concentrat\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:43
L9	16510	6 and 7	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:40
L10	110	7 and 8	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:40
L11	5032124	(graph\$4 curve line)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:41
L12	2128504	ratio	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:41
L13	714	8 and 12 same 11	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:41
L14	55996	(atom\$4 element\$4 doping dopant) near2 12	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:43
L15	1474708	concentrat\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:43

L16	103012	12 with 15	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:44
L17	34916	12 near3 15	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:44
L18	1593	17 with 11	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:45
L19	12	18 and 7	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:46
L20	2	"5242855".pn.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 16:27
L21	268	((438/505) or (438/607) or (438/934)).CCLS.	USPAT; USOCR	OR	OFF	2005/09/28 16:31
L22	268	((438/505) or (438/607) or (438/934)).CCLS.	USPAT; USOCR	OR	OFF	2005/09/28 16:34
L23	7	(calibrat\$4 and (dopant dopiing)).ti.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 16:33
L24	1631	((438/14) or (438/505) or (438/607) or (438/934)).CCLS.	USPAT; USOCR	OR	OFF	2005/09/28 16:34
S96	2	laicpms la-icpms la adj icpms	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 16:25
S97	1	Laser-Assisted adj Inductively adj Coupled adj Plasma adj Mass adj Spectrometry	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 17:55
S98	1	Laser adj Assisted adj Inductiv\$ adj Coupled adj Plasma adj Mass adj Spectrometr\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 17:56

S99	2	Laser adj Assisted adj4 Mass adj Spectrometr\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 17:58
S10 0	3112	Laser near6 Mass adj Spectrometr\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:54
S10 1	2261	Laser near4 Mass adj Spectrometr\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 17:58
S10 2	44103	Mass adj Spectrometr\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 17:59
S10 3	18447	laser near2 ablat\$6	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 17:59
S10 4	79	S103 near4 S102	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 17:59
S10 5	292606	calibrat\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 16:32
S10 6	2	S104 same S105	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 18:03
S10 7	38927	(atom\$4 element\$4 doping dopant) near concentrat\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:42
S10 8	11689609	matrix wafer epitax\$4 silicon semiconductor substrate device layer	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 18:07

S109	11	S107 near2 S105 with S108	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 18:10
S110	3210850	measur\$4 metrolog\$4 quantify\$4 graph\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 18:20
S111	27308	(doping dopant) near concentrat\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 18:21
S112	866	S110 near4 S111	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 18:21
S113	1	S112 same laser same S102	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 18:22
S114	3	S112 and laser same S102	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 18:22
S115	11	S112 same S102	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:00
S116	277	S107 near ratio	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:01
S117	138	S116 near4 S107	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:01
S118	2	S116 near4 S107 near4 (graph\$4 curv\$4 line)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:03

S11 9	30925	atom\$4 near ratio	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:41
S12 0	4874	atom\$4 near concentrat\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:49
S12 1	76	S119 near4 S120	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:04
S12 2	5	S119 near4 S120 with (graph\$4 curve line)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:40
S12 3	5764	S119 near2 (versus vs "vs.") S120	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:07
S12 4	2	S119 near2 (versus vs "vs.") near2 S120	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:07
S12 5	2	"6855647".pn.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:20
S12 6	1	S125 and S119 and S120	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:33
S12 7	7561488	boron b indium arsenic copper cu	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:36
S12 8	1	S125 and S127	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:35

S12 9	1711	methylosiloxane	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:35
S13 0	5357	methyl near2 siloxane	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:35
S13 1	0	(S129 S130) and S125	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:36
S13 2	928819	boron indium arsenic copper	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:36
S13 3	156793	doping dopant	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:36
S13 4	0	(S129 S130) with S132 near2 S133	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:37
S13 5	2	(S129 S130) with S132 with S133	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:37
S13 6	71	(S129 S130) with S132	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:38
S13 7	15	Laser near2 ablat\$6 near2 Mass adj Spectrometr\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:55
S13 8	0	Laser near2 ablat\$6 near2 plasma near2 Mass adj Spectrometr\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/27 19:55

S13 9	18945	etsu.as.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:28
S14 0	292606	calibrat\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:30
S14 1	51	S139 and S140	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:28
S14 2	21999	calibration adj curve	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:30
S14 3	19	S139 and S142	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:30
S14 4	4	("4429047").PN. OR ("5841532"). URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2005/09/28 13:32
S14 5	9709	doping adj concentration	US-PGPUB; USPAT; USOCR	OR	OFF	2005/09/28 13:38
S14 6	825370	substrate wafer	US-PGPUB; USPAT; USOCR	OR	OFF	2005/09/28 13:32
S14 7	26	S142 and S145 and S146	US-PGPUB; USPAT; USOCR	OR	OFF	2005/09/28 13:32
S14 8	4	("5042952" "5377006" "5706094" "6118533").PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2005/09/28 13:36
S14 9	3814705	surface	US-PGPUB; USPAT; USOCR	OR	OFF	2005/09/28 13:38
S15 0	1019848	concentration	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/28 13:39
S15 1	12383	S149 near S150	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/28 13:40

S15 2	6320	S149 adj S150	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/28 13:40
S15 3	30925	atom\$4 near ratio	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:41
S15 4	13	S152 with S153	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:43
S15 5	4	S152 with S142	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:43
S15 6	5	S152 same S142	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:49
S15 7	16510	S146 near manufactur\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:39
S15 8	4874	atom\$4 near concentrat\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 15:39
S15 9	84	S157 and S153	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:50
S16 0	0	S157 and S153 and S142	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:50
S16 1	7	S157 and S153 and S140	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/28 13:50



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... Width **ratio** = **ratio** of absorption width to source width. Cont. ...

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At Inlet Orange, the maximum **atomic ratio** was due a lesser **concentration** of ...

Smith, SV (1984), Phosphorus **versus** nitrogen limitation in the marine ...

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A plot of the N to In surface **atomic ratio versus** incident angle is shown in

figure 6. ... that the **atomic concentration ratios** are similar (within ...

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Sn **atomic ratio** 2. :. 1 were annealed in. oxygen at different pressures. ...

Electron **concentration** N **versus** **atomic** content of cadmium. CCd. The full curve ...

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The first type of **atomic** spectrometry used in this experiment is **atomic** ...

Construct separate calibration plots of absorbance **versus concentration** for Ca ...

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discharge, the tritium **concentration** in the **atomic ratio** becomes T/C=0.1. ...

7 shows the deuterium **concentration versus** the discharge ...

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